

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	156319	(magnetic adj (head element apparatus sensor))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 09:55
L2	970	1 and (read adj gap)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 09:56
L3	106	1 and (A\$1L\$1D (atomic adj layer\$2 adj deposition))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:00
L4	1450	1 and ((B! boron) near4 (oxide nitride))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 09:57
L5	121	1 and ((Be! beryllium) near4 (oxide nitride))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 09:57
L6	2953	1 and (Al\$1N ((Al! aluminum) near4 nitride) ("Al?sub.\$2" adj "N?sub.\$2"))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 09:58
L7	4670	1 and (Al\$1O ((Al! aluminum) near4 oxide) ("Al?sub.\$2" adj "O?sub.\$2"))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:29
L8	0	2 and 3 and (4 5) and (6 7)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 09:58
L9	0	2 and 3 and (4 5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 09:58
L10	2	2 and 3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 09:58

L11	56	1 and ((A\$1L\$1D (atomic adj layer\$2 adj deposition)) and gap)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:41
L12	54	11 not 10	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:09
L13	1073	1 and 6 and 7	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:09
L14	1526	1 and (4 5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:09
L15	202	13 and 14	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:09
L16	2	15 and 2	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:11
L17	27	15 and (gap same (lamine composite plural (oxide and nitride)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:21
L18	2	"6709767"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:22
L19	2	"6780524"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:24
L20	8	("6198608" "6329087" "6452757" "20010013997" "20010014412" "20020024780" "20020054463" "20020081457").pn.	US-PGPUB; USPAT	OR	ON	2005/04/21 10:29

L21	176	7 and (gap near4 (Al\$1O ((Al! aluminum) near4 oxide) ("Al?sub.\$2" adj "O?sub.\$2"))))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:36
L22	4	("20010013997" "20020057538" "20020145834" "6414825").pn.	US-PGPUB; USPAT	OR	ON	2005/04/21 10:35
L23	363	ALCVD	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:36
L24	8	1 and 23	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:39
L25	20	1 and (atomic adj layer adj chemical adj vapor adj deposition)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:41
L26	0	1 and (atomic adj layer adj c\$1v\$1d)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:40
L27	0	(25 26) not (12 17 24)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:40
L28	0	25 not (12 17 24)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:40
L29	3104	(A\$1L\$1D (atomic adj layer\$2 adj deposition) a\$1l\$1c\$1v\$1d (atomic adj layer adj chemical adj vapor adj deposition)) same (sputtering (chemical adj vapor adj deposition) c\$1v\$1d)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:44
L31	16	29 and @PY="1999"	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/04/21 10:44